

Day : Thursday
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Inventor Name Search Result

Your Search was:

Last Name = SHIMODA

First Name = ATSUSHI

Application#	Patent#	Status	Date Filed	Title	Inventor Name 15
10242362	Not Issued	030	09/13/2002	IMAGE DETECTION METHOD AND ITS APPARATUS AND DEFECT DETECTION METHOD AND ITS APPARATUS	SHIMODA, ATSUSHI
10218463	Not Issued	030	08/15/2002	METHOD AND APPARATUS FOR INSPECTING PATTERN DEFECTS	SHIMODA, ATSUSHI
10050778	Not Issued	030	01/18/2002	APPARATUS AND METHOD FOR INSPECTING PATTERN	SHIMODA, ATSUSHI
10012380	6556955	150	12/12/2001	METHOD OF DETERMINING LETHALITY OF DEFECTS IN CIRCUIT PATTERN INSPECTION, METHOD OF SELECTING DEFECTS TO BE REVIEWED, AND INSPECTION SYSTEM OF CIRCUIT PATTERNS INVOLVED WITH THE METHODS	SHIMODA, ATSUSHI
09944858	Not Issued	071	08/31/2001	METHOD AND APPARATUS FOR INSPECTING DEFECTS OF A SPECIMEN	SHIMODA, ATSUSHI
09783604	Not Issued	030	02/15/2001	A METHOD AND SYSTEM FOR ANALYZING CIRCUIT PATTERN DEFECTS	SHIMODA, ATSUSHI
09743560	Not Issued	061	01/09/2001	METHOD FOR OBSERVING SPECIMEN AND DEVICE THEREFOR	SHIMODA, ATSUSHI
09553944	6456951	150	04/21/2000	METHOD AND APPARATUS FOR PROCESSING INSPECTION DATA	SHIMODA, ATSUSHI
09421093	6476388	150	10/19/1999	SCANNING ELECTRON MICROSCOPE, DEFECT	SHIMODA, ATSUSHI

				PORTION ANALYZING METHOD USING THE SAME AND APPARATUS AND METHOD OF AUTOMATICALLY SAMPLING IMAGE THEREOF	
09225513	6334097	150	01/06/1999	METHOD OF DETERMINING LETHALITY OF DEFECTS IN CIRCUIT PATTERN INSPECTION METHOD OF SELECTING DEFECTS TO BE REVIEWED AND INSPECTION SYSTEM OF CIRCUIT PATTERNS INVOLVED WITH THE METHODS	SHIMODA , ATSUSHI
08960954	Not Issued	161	10/30/1997	METHOD FOR THE CONTROLLED FORMATION OF VOIDS IN DOPED GLASS DIELECTRIC FILMS	SHIMODA , ATSUSHI
08564922	5719084	150	11/29/1995	METHOD FOR THE CONTROLLED FORMATION OF VOIDS IN DOPED GLASS DIELECTRIC FILMS	SHIMODA , ATSUSHI
08179166	Not Issued	166	01/10/1994	METHOD FOR THE CONTROLLED FORMATION OF VOIDS IN DOPED GLASS DIELECTRIC FILMS	SHIMODA , ATSUSHI
08023650	Not Issued	163	02/26/1993	METHOD FOR FORMING A THICK DOPED GLASS DIELECTRIC FILM WITHOUT VOIDS	SHIMODA , ATSUSHI
08023304	5278103	150	02/26/1993	METHOD FOR THE CONTROLLED FORMATION OF VOIDS IN DOPED GLASS DIELECTRIC FILMS	SHIMODA , ATSUSHI

Inventor Search Completed: No Records to Display.

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